



# Ultra High Temperature Probe Card Solution for Automotive IC Testing



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# Agenda

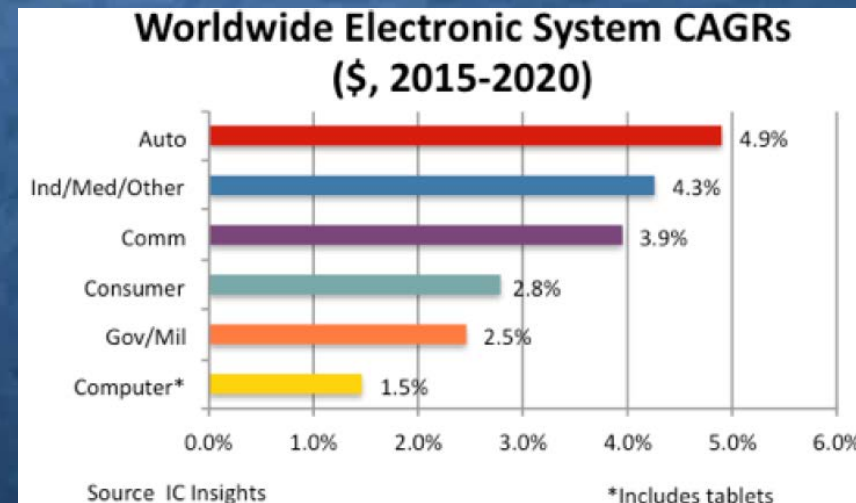
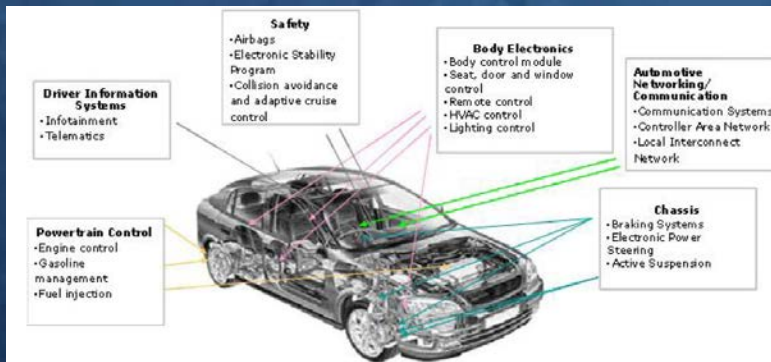
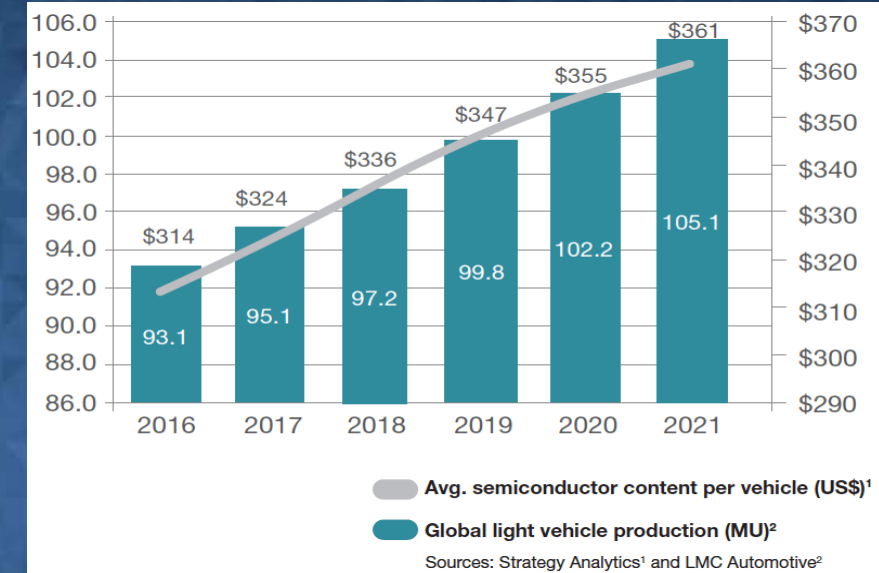
- **Automotive IC Market Overview**
- **Automotive IC Test Requirements and Probe Card Challenges**
- **FormFactor Ultra High Temperature Probe Card Solution**
- **Probe Characterization Result Under Ultra High Temperature Testing Environment**
- **Actual Probe Card Performance Result by Leading Automotive IC Customer**
- **Summary and Acknowledgement**

# Automotive Semiconductor Market Overview

## Drive Demand of New Testing Solution

- **Automotive electronics is a fast-growing market**

- Predictions are between 3%~12% CAGR over next 5 years
- Average number of semiconductors in a car increases significantly in modern cars
- Key drivers for automotive IC growth
  - Critical safety system
  - Increased fuel efficiency
  - Navigation and communication
  - Comfort & entertainment features





# Automotive Safety Consideration: Zero Defect Expectation

- IC manufacturers adopt Zero Defects Parts per Million (DPPM) design methodology and test to this standard

- Finding a golf ball in baseball field

- **Reasons:**

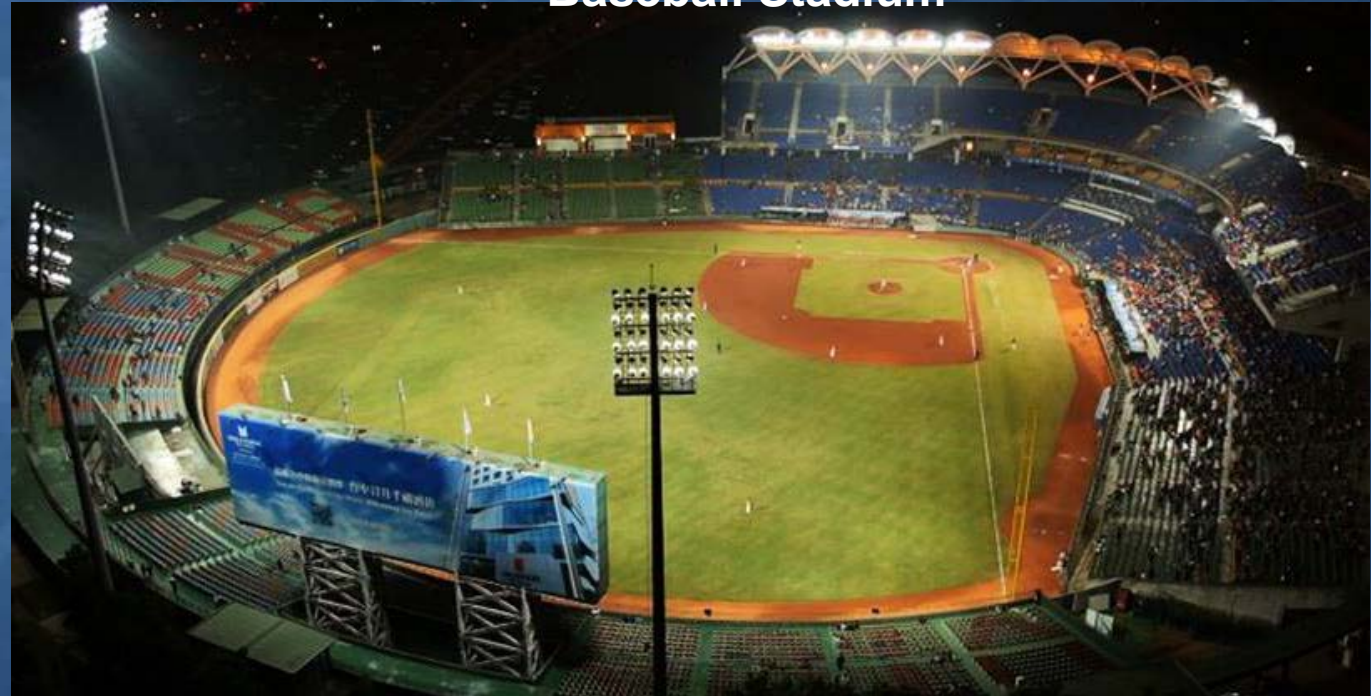
- Failure rate at the automotive level is higher
- massive recall and serious economic distress

- **Probing Requirement:**

- No Dielectric punch-through

**ZERO DEFECTS**

Taichung Intercontinental  
Baseball Stadium



# Automotive IC Wafer Sort Test Challenges

- **Harsh outdoor environment**
- **Testing at full thermal range**
- **Minimize bond pad reliability impact**
- **Support large volume demand**
- **Lower test cost**

## Probe card requirements:

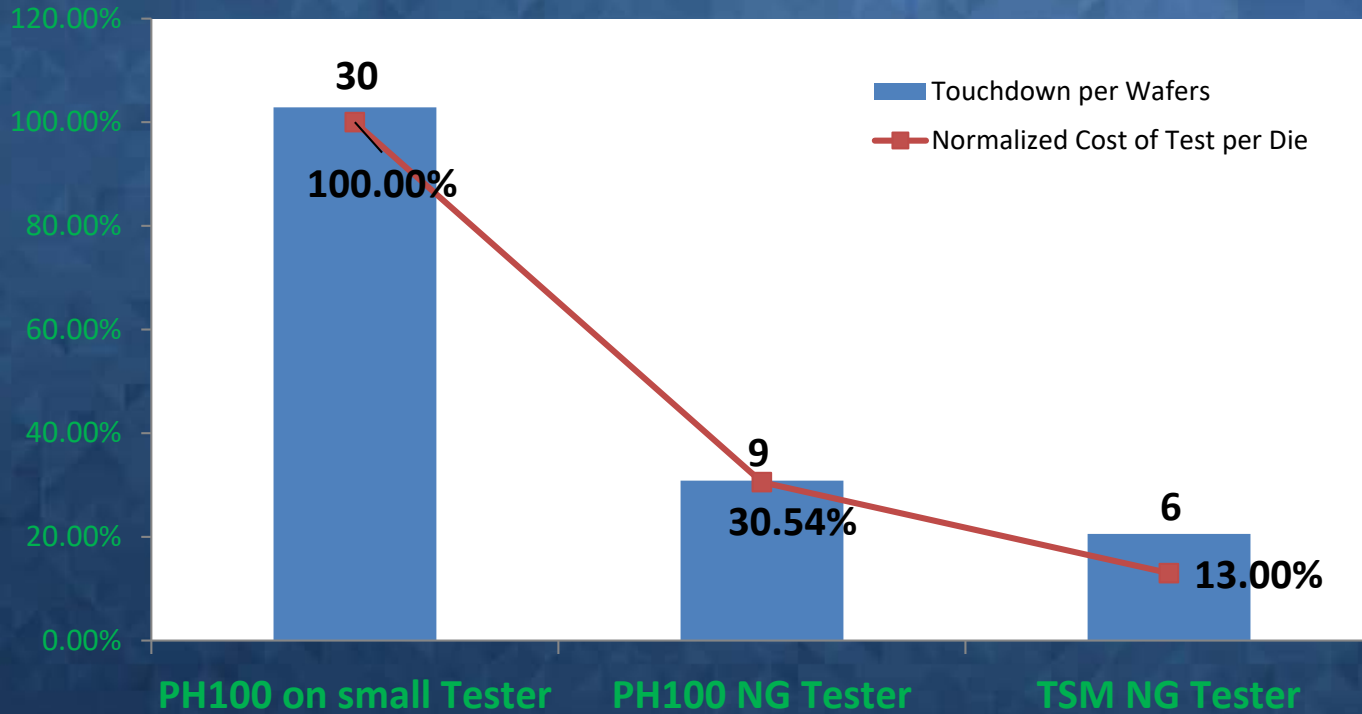
- Wafer sort test with multiple insertion: cold, room, hot temp
- High temp test required  
125°C → 150°C → 175°C
- Multiple TD at same bond pad
- Large active area + high parallelism for SoCs



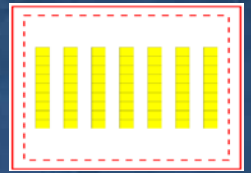
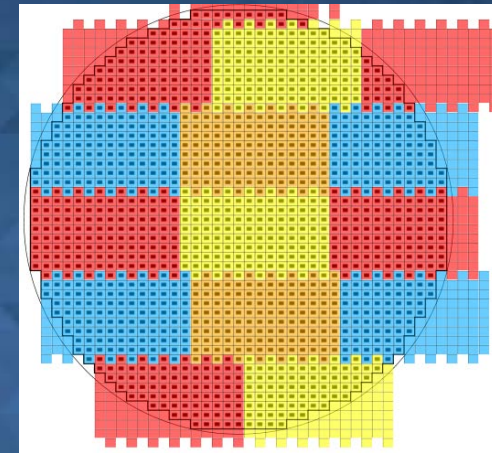
# Increase Test Efficiency = Reduce Cost of Test

Maximize Number of DUTs to Reduce Number of TDs

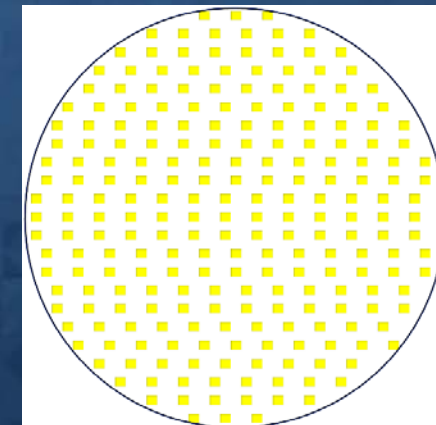
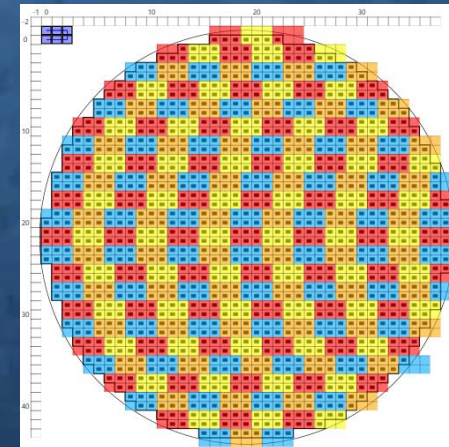
- Require Full Wafer Touch Down Maximize Touch Down Efficiency
- Increase Touch Down Efficiency to Reduce Cost of Test



30 TD 63 DUT PH100 Touch Down Pattern



6 TD 234 DUT Full Wafer Contact TD Pattern



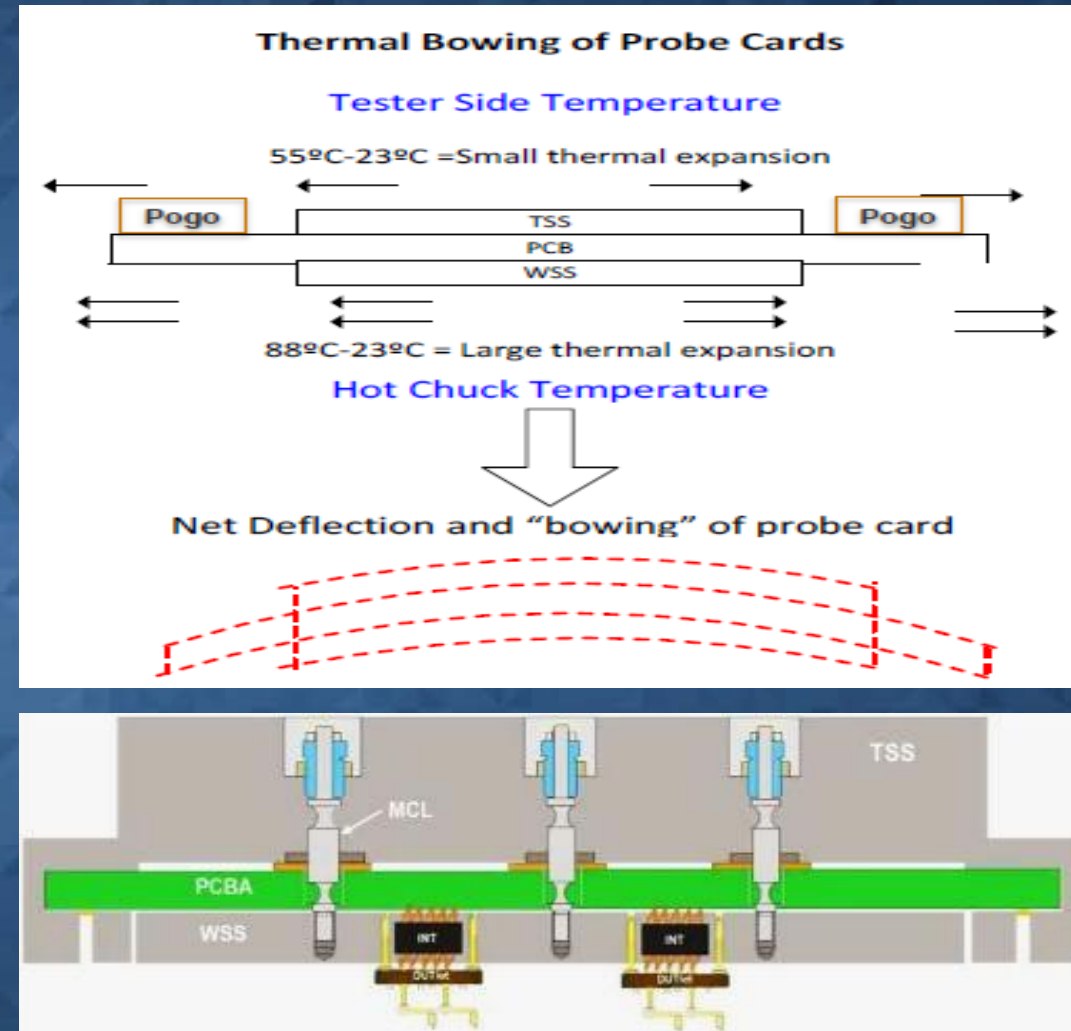
# TrueScale Matrix Probe Card

## Thermal Planarity Control

- Thermal gradients in probe card produce differential expansion across probe card components and can produce probe card bow

- Design and build the probe card for better thermal planarity control

- Mechanical simulation to understand thermal behavior
- Design automation (real-time probe card deformation simulation) to optimize Mechanical Coupling Link location for planarity control
- Added flexible shim kit design on inner tester side stiffener
- Bridge beam hardware add to PC outgoing PXI metrology tool to simulate test head docking condition for planarity adjustment
- AOT/POT analysis on field to further understand deflection force





# TrueScale Matrix Probe Card Architecture

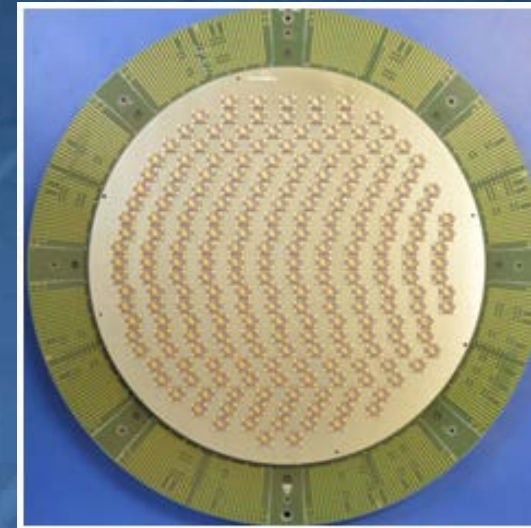
Optimize for High Parallelism and Ultra High Temperature

- **Probe Card Design Requirements**

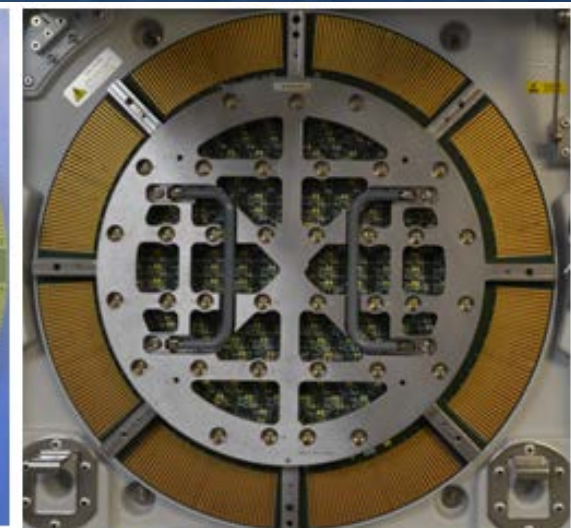
- 300mm probing active area
- Support >256 DUTs, >35000 Probe Count
- Smallest Pad Size and Pitch: ~55um/65um
- Temperature Range: -40 to +165°C

- **TSM PC Achieved Large Active Area with Highest Parallelism**

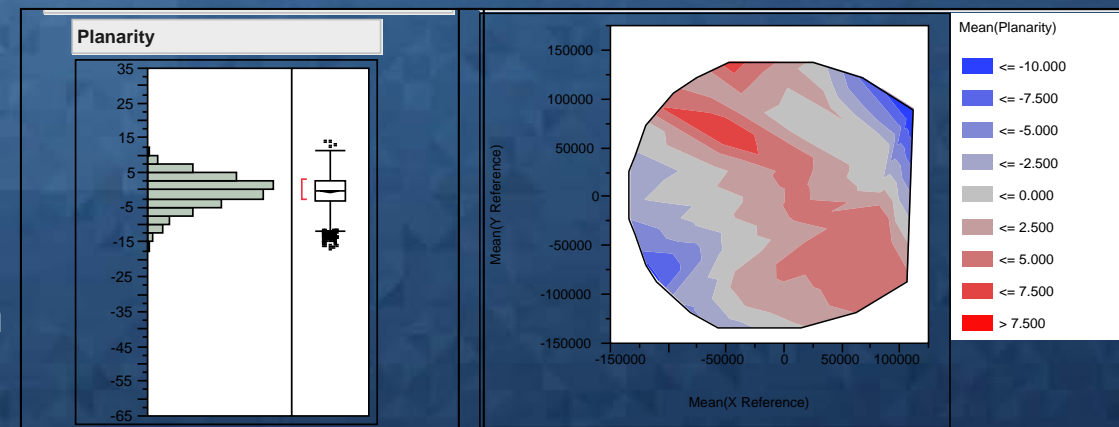
- Full 300mm active area probing to improve touchdown efficiency
- FFI proprietary touchdown efficiency analysis software and service
- T11 UHT Probe Rated -40 to +175°C
- Modified TSS and Matrix architecture achieved 30um planarity



Custom Wafer Side Stiffener for wide temp range operation



Modified Tester Side Stiffener





# DragonBlade T11.4 Ultra High Temperature Probe

Metric	T11	T11.4 UHT
Max Temperature (°C) / AOT (um)	<=130°C/75um <=160°C/65um	<b>175°C/100um</b>
Min pad Pitch (um)	50um	60um
Scrub Ratio	~10%	
Current Carrier Capacity (ISMI)	1.2A	>1A
Typical spring constant (gram-force / mil)	0.8 g/mil	
Tip sizes at beginning of life (um)	6um, 8.5um, or 14um ±3um	
Tip sizes at end of life (um)	20um	

# Final Result in Production Test Environment

- **Renesas agreed to share their collecting data.**
  - Beam creep data
  - Contact Resistance
  - Probe Mark Characterization Data
  - Probe Mark Photos



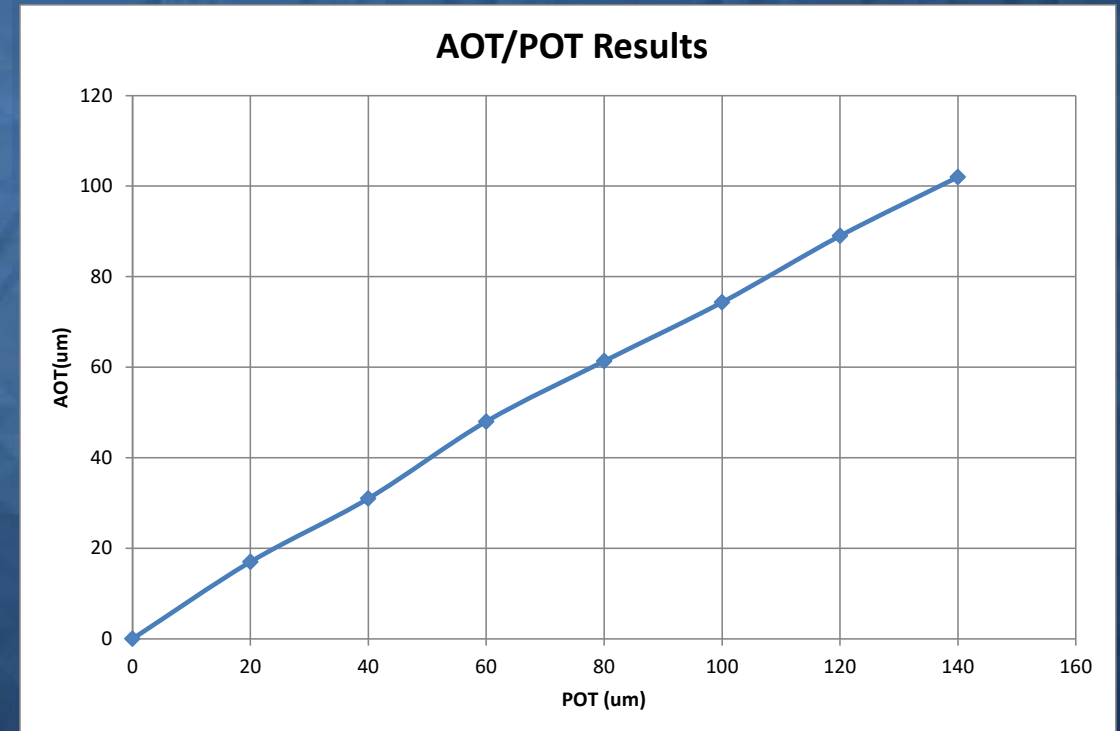
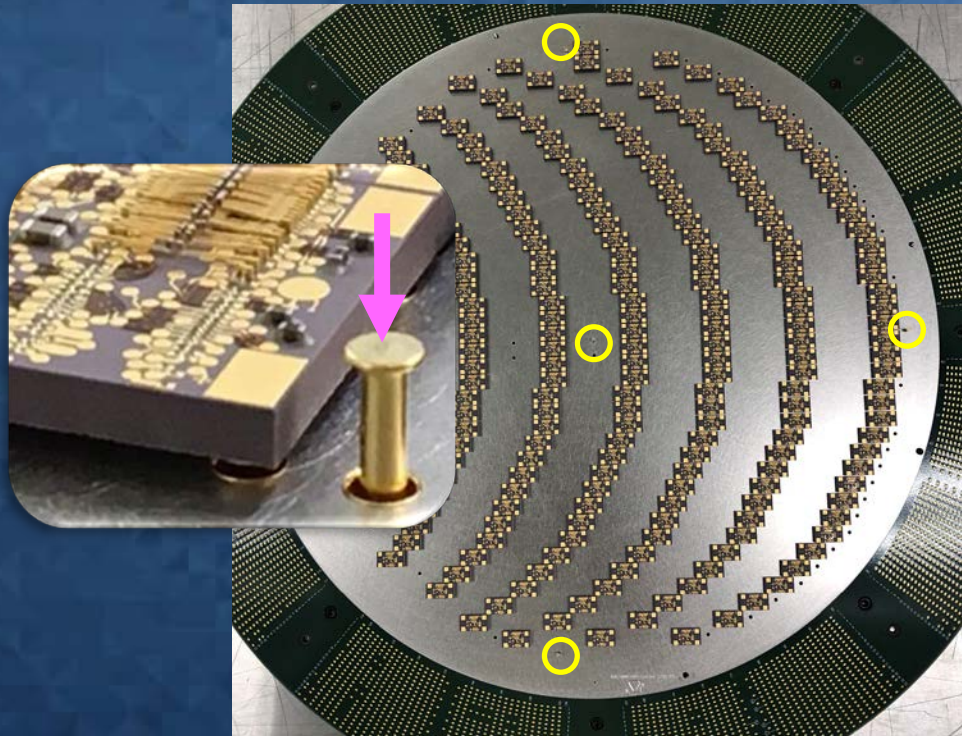


# Actual Over-Travel vs. Program Over-Travel Analysis

- **Using Pin and Sleeve to analyze probe actual over-travel**

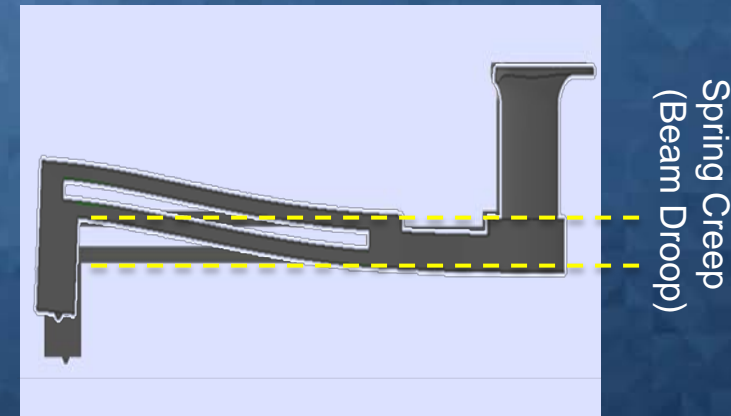
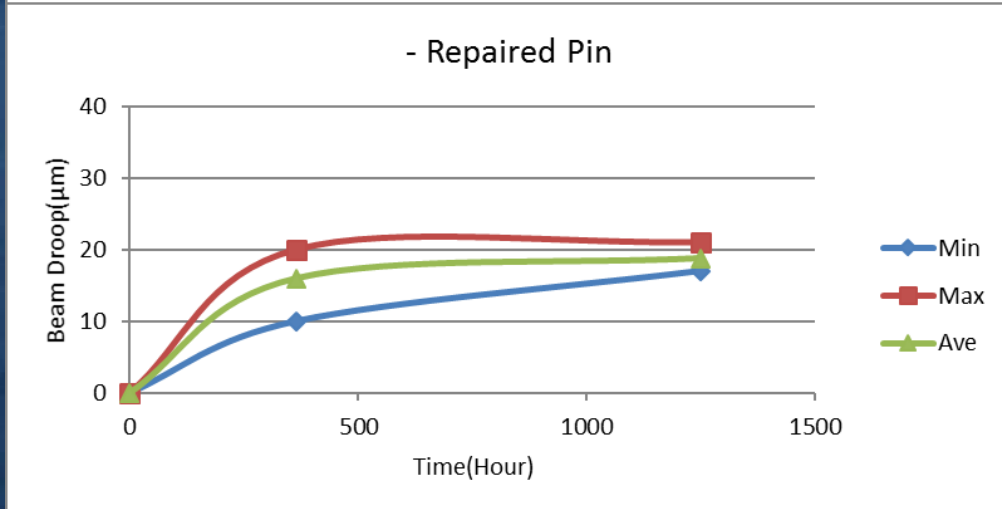
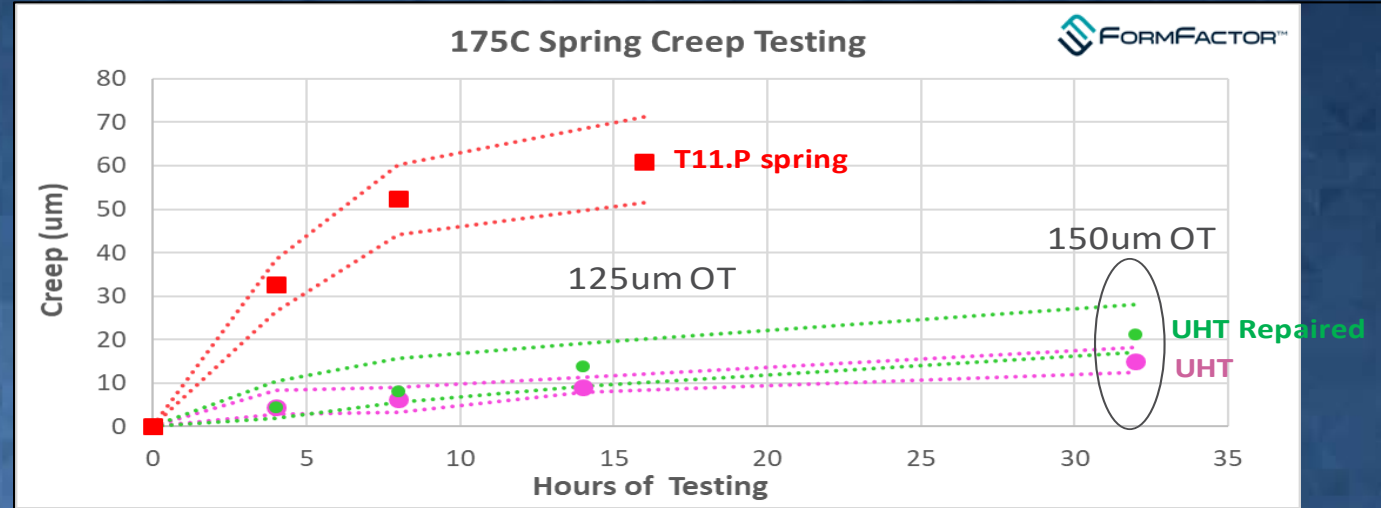
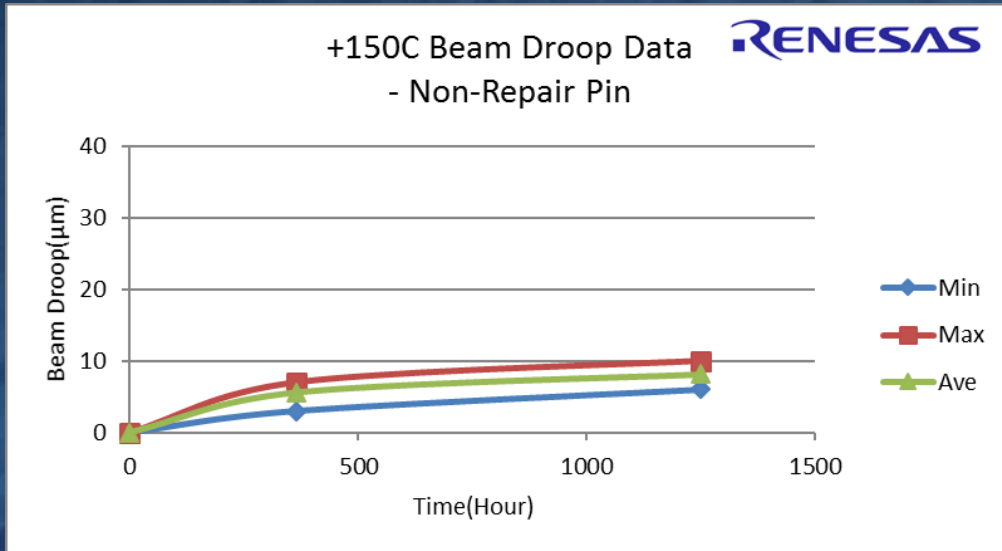
Install Pin & Sleeve at 5 locations on the PH.  
Check that the pins have shifted upwards  
due to the chuck loading

AOT/POT Results  $\approx 75\%$



# DragonBlade T11.4 UHT Performance

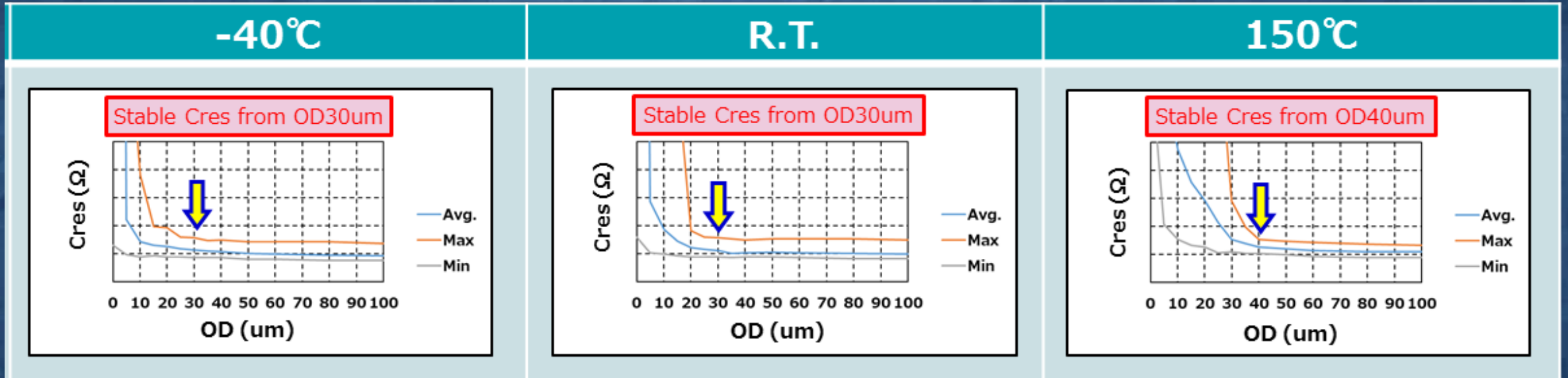
## Same capability as T11 with 2x hot temp performance





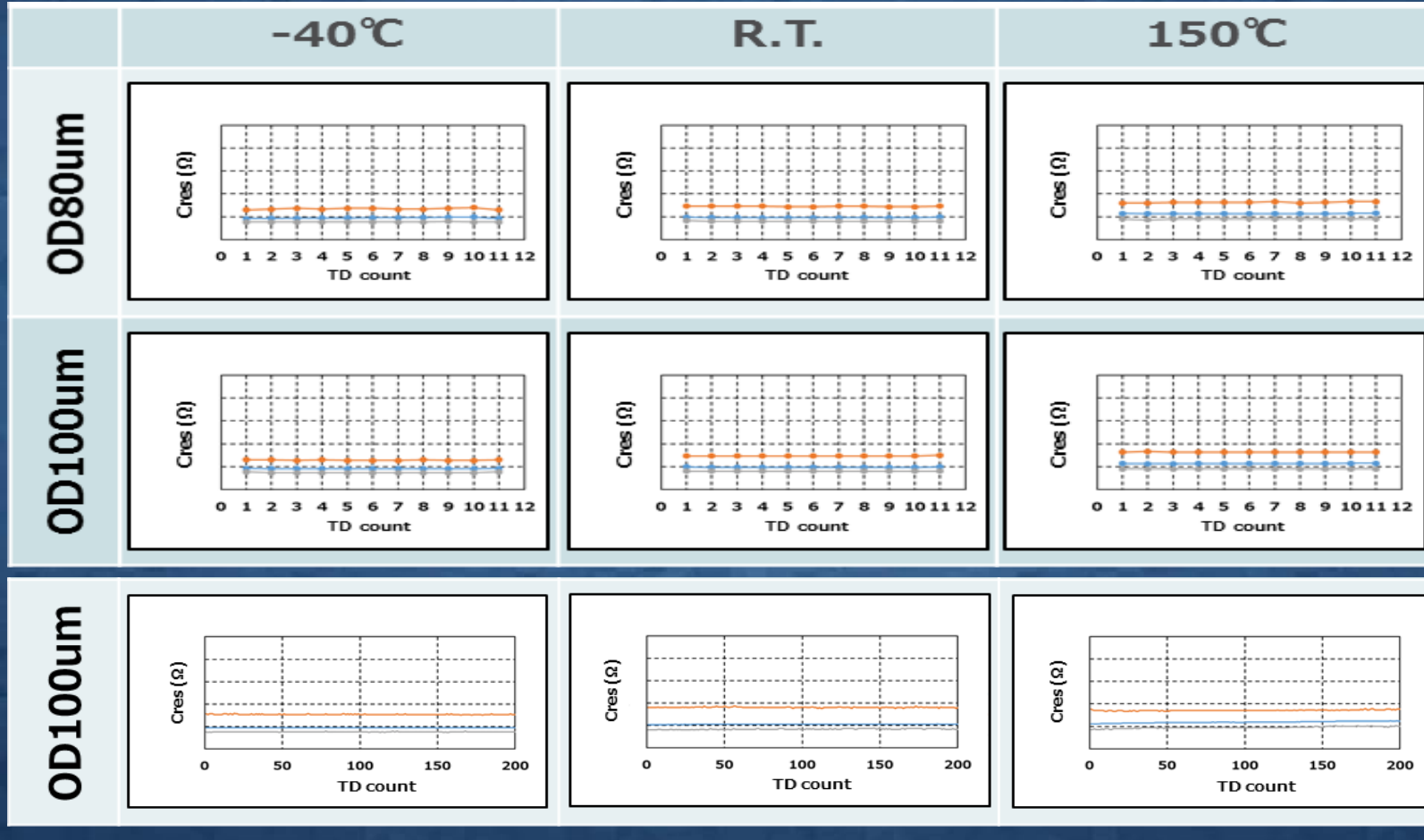
# Contact Resistance vs. OverDrive

- T11.4 UHT archived stable Cres from 30-40 $\mu$ m OD.



# Multi-Contact Performance

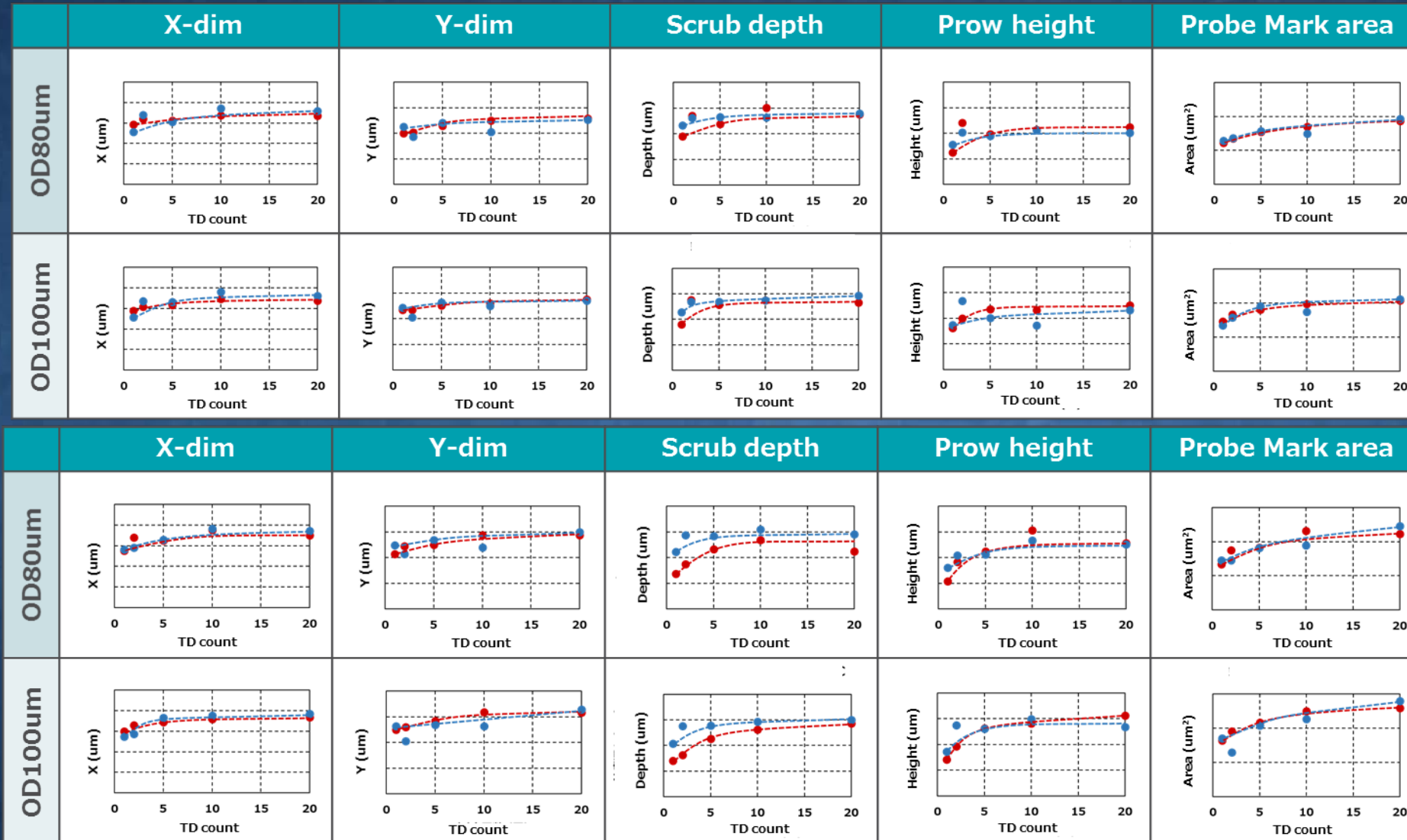
- **T11.4 UHT archived stable Cres for all cases.**
  - 10 times TD and move to new surface at 11<sup>th</sup> TD and 200 times TD test





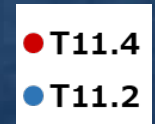
# T11.4 UHT Probe Mark Size Analysis

## Probe Mark Size Past Extreme Temperature Test



Prober Chuck Temperature: -40°C

Prober Chuck Temperature: 160°C



# T11.4 UHT Probe Mark and Pad Reliability Analysis

## No Under Pad Damage at 20TD

	Single TD	Multi-TD : 5 times	Multi-TD : 20 times
OD80um			
OD100um			
	Single TD	Multi-TD : 5 times	Multi-TD : 20 times
OD80um			
OD100um			

Cold  
Temperature:  
-40°C

Hot  
Temperature:  
160°C



# Summary

- **Automotive IC market continues growing with large demand and zero defects parts**
- **FormFactor Matrix platform with T11 Ultra High Temp probe provides capability of meeting zero defect testing requirement and the highest testing efficiency for automotive IC wafer sort test**
- **TrueScale Matrix with T11 UHT probe solution has been validated by key automotive customer and deployed to various tester platforms including T2000, V93K DD, J750**



# Acknowledgement

## Special Thanks!



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